Chemical Vapour Deposition coating - Soft to medium hard substrate

402

Grinding

	Steps	PG	FG	FG 2
Surface	Type	SiC Foil #320	MD-Largo	MD-Largo
	Disc speed (rpm)	300	150	150
Abrasive	Type		DiaPro Allegro/Largo 9 µm	DiaPro Largo 3 µm
	Predosing/dosing		3/6	3/6
Lubricant	Type	Water		
	Predosing/dosing			
	Force (N)	30	40	40
	Holder direction	>>	>>	>>>
	Holder speed (rpm)	150	150	150
	Time (min)	1	4	3

Polishing

	Steps	DP	OP
Surface	Type	MD-Dac	MD-Chem
	Disc speed (rpm)	150	150
Abrasive	Type	DiaPro Dac 3 µm	OP-A, 0.1 µm
	Predosing/dosing	3/10	1/10
Lubricant	Type		
	Predosing/dosing		
	Force (N)	30	15
	Holder direction	>>	>>
	Holder speed (rpm)	150	150
	Time (min)	2	1

Method comments

The method is developed to fit a standard equipment configuration with 30 mm specimen on 300mm disc. Dosing levels are valid for following equipment: Tegramin, AbraPol and LaboPol

For advice on how to adjust the method to fit your equipment, please take a look at Preparation Parameters.

The preparation time for the plane grinding (PG) step depends very much on the condition of the samples and if they are prepared as single specimens or clamped in a specimen holder. Please check the samples after the first step and repeat it if necessary.

Take a look at Preparation Parameters